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**INFORMATION DISCLOSURE
STATEMENT BY APPLICANT**
(Not for submission under 37 CFR 1.99)

Application Number	10779373
Filing Date	2004-02-17
First Named Inventor	SCHAEPKENS, et al.
Art Unit	1794
Examiner Name	Kevin R. Krueer
Attorney Docket Number	GER01 006

U.S.PATENTS

Examiner Initial*	Cite No	Patent Number	Kind Code ¹	Issue Date	Name of Patentee or Applicant of cited Document	Pages, Columns, Lines where Relevant Passages or Relevant Figures Appear
	1	6777871	B2	2004-08-17	Duggal et al.	
	2	6642652	B2	2003-11-04	Collins, III et al.	
	3	6576351	B2	2003-06-10	Silvernail	
	4	6522067	B1	2003-02-18	Graff et al.	
	5	6413645	B1	2002-07-02	Graff et al.	
	6	6291116	B1	2001-09-18	Wolk et al.	
	7	6268695	B1	2001-07-31	Affinito	
	8	6097147	A	2000-08-01	Baldo et al.	

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9	6023371	A	2000-02-08	Onitsuka et al.	
10	5998803	A	1999-12-07	Forrest et al.	
11	5757126	A	1998-05-26	Harvey et al.	
12	5736207	A	1998-04-07	Walther et al.	
13	5683757	A	1997-11-04	Iskanderova et al.	
14	5654084	A	1997-08-05	Egert	
15	5462779	A	1995-10-31	Misiano et al.	
16	5185391	A	1993-02-09	Stokich	
17	4552791	A	1985-11-12	Hahn	
18	4540763	A	1985-09-10	Kirchhoff	
19	3932693	A	1976-01-13	Shaw et al.	

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	1	0026973	WO	A1	2000-05-11	Delta V Technologies, Inc.		<input type="checkbox"/>
	2	0181649	WO	A1	2001-11-01	Battelle Memorial Institute		<input type="checkbox"/>
	3	0182366	WO	A2	2001-11-01	Battelle Memorial Institute		<input type="checkbox"/>
	4	2004098525	JP	A	2004-04-02	Sumimoto Heavy Ind Ltd		<input type="checkbox"/>

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Examiner Initials*	Cite No	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc), date, pages(s), volume-issue number(s), publisher, city and/or country where published.	T ⁵
	1	H. SUZUKI et al., Near-Ultraviolet Electroluminescence from Polysilanes, 331, Thin Solid Films, p. 64-70, 1998.	<input type="checkbox"/>

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2	Gijsbert Jan MEEUSEN, "Plasma Beam Deposition of Amorphous Hydrogenated Silicon", Thesis, University of Eindhoven, p. 16-19 (1994).	<input type="checkbox"/>
3	V.J. LAW et al., "RF Probe Technology for the Next Generation of Technological Plasmas," J. Phys. D.: Appl. Phys., 34, p. 2726-2733, 2001.	<input type="checkbox"/>
4	Bastiaan Arie KOREVAAR, "Integration of Expanding Thermal Plasma Deposited Hydrogeneated Amorphous Silicon in Solar Cells," Thesis, University of Eindhoven, p. 23-34, 2002.	<input type="checkbox"/>

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